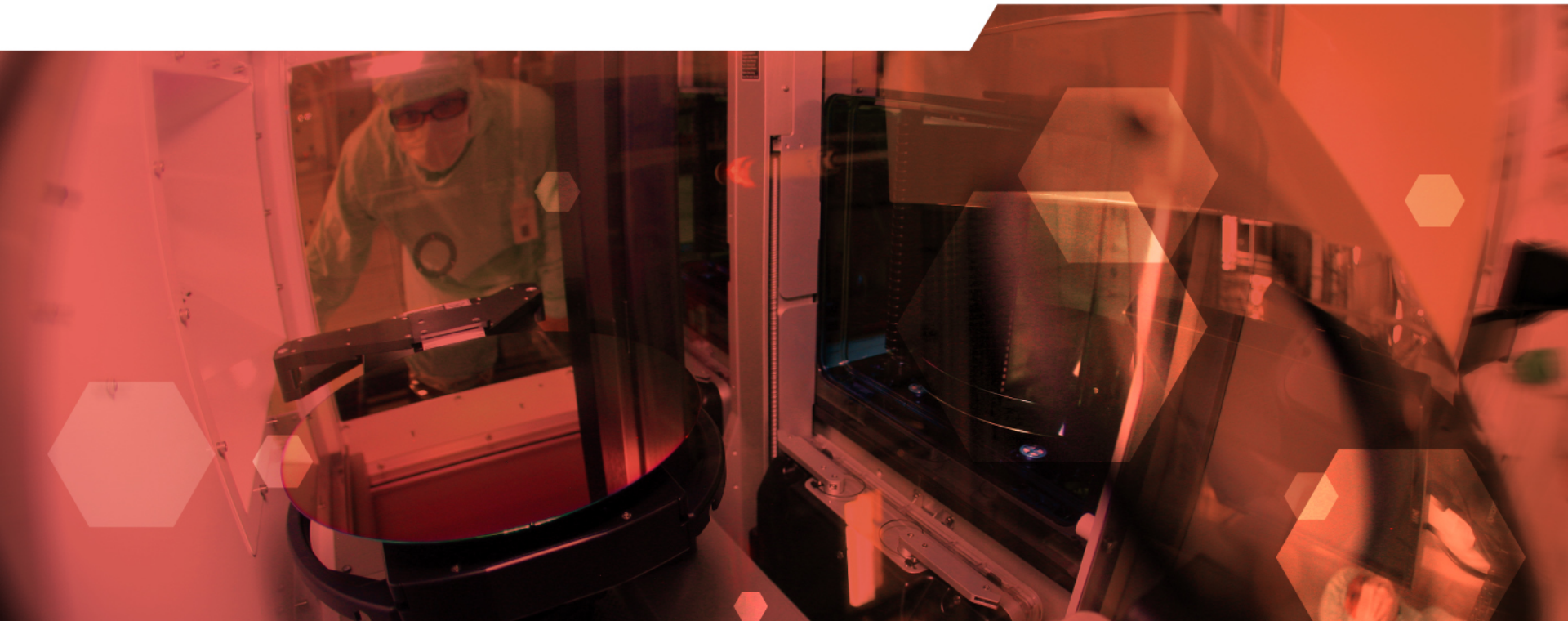


SEMI Staff Report

November 2019

v4



SEMI Global Upcoming Calendar of Events

Event Name	Event Details
SEMICON[®] EUROPA	Nov 12-15, 2019 Munich, Germany
SEMICON[®] JAPAN	Dec 11-13, 2019 Tokyo, Japan
SEMICON[®] KOREA	Feb 5-7, 2020 Seoul, Korea

Standards Meetings this week

Sunday	Monday	Tuesday	Wednesday	Thursday	Friday	Saturday
	4	5	6	7	8	9
				3DP&I		
		EH&S				
	Facilities & Gases					
	Information & Control					
	Liquid Chemicals					
	MEMS/NEMS					
	NARSC	Metrics				
		Physical Interfaces & Carriers				
				Traceability		

**Schedule
at-a-glance**

SEMI Standards Networking Event

Tuesday, November 5
5:30 PM to 7:00 PM

SEMI
673 S. Milpitas Blvd.
Milpitas, California 95035

Upcoming NA Meetings

Event Name	Date / Venue
NA Standards Spring 2020 Meetings	March 30- April 2, 2020 SEMI HQ, Milpitas, California
SEMICON West 2020	July 20-23, 2020 San Francisco, California [MOSCONE South Hall]
NA Standards Fall 2020 Meetings	November 2-5, 2020 [tentative] SEMI HQ, Milpitas, California

Critical Dates for SEMI Standards Ballots

2019	Ballot Submission Deadline	Voting Opens	Voting Closes
Cycle 8	October 11	October 25	November 25
Cycle 9	November 14	November 26	December 26
2020			
Cycle 1	January 6	January 15	February 14
Cycle 2	January 30	February 11	March 12
Cycle 3	March 11	March 25	April 24
....			

<https://www.semi.org/en/collaborate/standards/ballots>

SEMI Standards Publications

Cycle	New	Revised	Reapproved	Withdrawn
July 2019	2	3	0	0
August 2019	2	12	5	0
September 2019	1	1	1	0
October 2019	2	9	2	0

- Total SEMI Standards in portfolio: 1,010
 - Includes 269 Inactive Standards

SEMI Standards Publications

New Standards

Cycle	Designation	Title	Committee	Region
July 2019	SEMI S30	Safety Guideline for Use of Energetic Materials in Semiconductor R&D and Manufacturing Processes	EHS	NA
July 2019	SEMI 3D20	Specification for Panel Characteristics for Panel Level Packaging (PLP) Applications	3D-IC	NA
August 2019	SEMI A3	Specification for Printed Circuit Board Equipment Communication Interfaces (PCBECI)	Automation Technology	TW
August 2019	SEMI HB11	Specification for Sapphire Single Crystal Ingot Intended for Use for Manufacturing HB-LED Wafers	HB-LED	CH

SEMI Standards Publications

New Standards

Cycle	Designation	Title	Committee	Region
September 2019	SEMI E177	Specification for Transmission Electron Microscope (TEM) Lamella Carriers Used in Electron Microscopy Workflow	PIC	NA
October 2019	SEMI 3D21	Guide for Describing Glass-Based Material for Use in 3DS-IC Process	3D-IC	NA
October 2019	SEMI PV91	Specification for Trichlorosilane Used in Polysilicon Production	Photovoltaic	CH

SEMI Standards Publications

Inactive Standards

Committee	Number of Inactive Standards
Assembly & Packaging	48
Automated Test Equipment	2
Compound Semiconductor Materials	4
Environmental Health & Safety	8
Facilities	15
FPD – Equipment	5
FPD – Factory Automation	14
FPD – Materials & Components	13
Gases	18

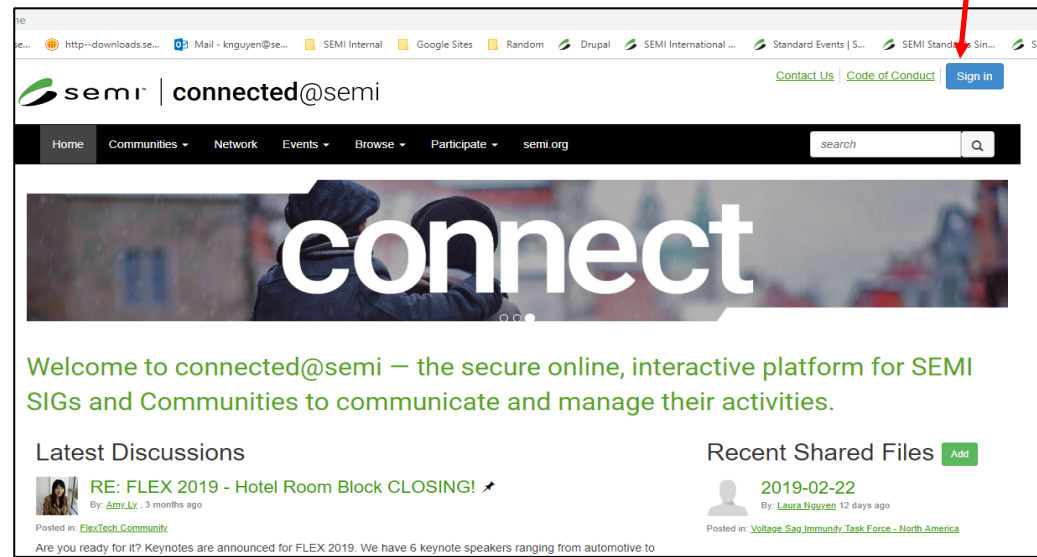
SEMI Standards Publications

Inactive Standards Cont.

Committee	Number of Inactive Standards
Information & Control	37
Liquid Chemicals	24
MEMS	3
Metrics	9
Micropatterning	30
Photovoltaic	1
Physical Interfaces & Carriers	19
Silicon Wafer	11
Traceability	8

Connect@SEMI Community

- Web link - <https://connect.semi.org>
 - Login using Standards account (username and password)
 - Join any task forces
 - Post discussion thread
 - Upload meeting TF minutes
 - Contact your staff if a TF Site is desired



Regulations, Procedure Manual, and Style Manual

- *Regulations* (Feb 28, 2019)
 - Latest version clarifies procedures applicable for Copyrighted Items and trademarks
- *Procedure Manual* (Feb 28, 2019)
- *Style Manual Version 6* (March 25, 2019)
 - Additions and revisions to harmonize with updated *Regulations* and *Procedure Manual*
 - Updates
 - *Company or Organization Trademarks* (Table 1, #1-24)
 - *Active vs. Passive Voice* (Table 4, #4-4)
 - *Word Usage* (Table 4, #4-5)
 - *New Safety Guideline Conformance Notice* (Table 8, #8-1)

Facilities & Gases

Nonconforming Titles (See PM Appendix 4)

- None

Facilities 5-Year Review

Designation #	Standard Title	Action By	Original TF assigned to
SEMI E76-0299 (Reapproved 0913)	Guide for 300 mm Process Equipment Points of Connection to Facility Services	West 2018	Facilities NA TC Chapter
SEMI F49-0200 (Reapproved 1213)	Guide for Semiconductor Factory Systems Voltage Sag Immunity	Fall 2018	Facilities NA TC Chapter
SEMI F50-0200 (Reapproved 1213)	Guide for Electric Utility Voltage Sag Performance for Semiconductor Factories	Fall 2018	Facilities NA TC Chapter
SEMI E70-1213	Guide for Tool Accommodation Process	Fall 2018	Facilities NA TC Chapter
SEMI E6-0914	Guide for Semiconductor Equipment Installation Documentation	Fall 2019	Facilities NA TC Chapter

Gases 5-Year Review [1/2]

Designation #	Standard Title	Action By	Assigned to
SEMI F43-0308 (Reapproved 0613)	Test Method for Determination of Particle Contribution by Point-of-Use Gas Purifiers and Gas Filters	Spring 2018	Filters & Purifiers TF
SEMI F59-0302 (Reapproved 0613)	Test Method for Determination of Filter or Gas System Flow Pressure Drop Curves	Spring 2018	Filters & Purifiers TF
SEMI F67-1101 (Reapproved 0713)	Test Method for Determining Inert Gas Purifier Capacity	West 2018	Filters & Purifiers TF
SEMI F68-1101 (Reapproved 0713)	Test Method for Determining Purifier Efficiency	West 2018	Filters & Purifiers TF
SEMI C14-95 (Reapproved 0913)	Test Method for Particle Shedding Performance of 25 cm Gas Filter Cartridges	West 2018	Filters & Purifiers TF
SEMI F36-0299 (Reapproved 0913)	Guide for Dimensions and Connections of Gas Distribution Components	West 2018	Filters & Purifiers TF

Gases 5-Year Review [2/2]

Designation #	Standard Title	Action By	Assigned to
SEMI F72-0214	Test Method for Auger Electron Spectroscopy (AES) Evaluation of Oxide Layer of Wetted Surfaces of Passivated 316L Stainless Steel Components	Spring 2019	Materials TF
SEMI F79-0914	Guide for Gas Compatibility with Silicon Used in Gas Distribution Components	Fall 2019	Materials TF
SEMI F105-0914	Guide for Metallic Material Compatibility in Gas Distribution Systems	Fall 2019	Materials TF
SEMI F60-1214	Test Method for ESCA Evaluation of Surface Composition of Wetted Surfaces of Passivated 316L Stainless Steel Components	Fall 2019	Materials TF
SEMI F73-1214	Test Method for Scanning Electron Microscopy (SEM) Evaluation of Wetted Surface Condition of Stainless Steel Components	Fall 2019	Materials TF

Five-Year Review (In-progress/Needs Action)

- Facilities
 - SEMI E51, Guide for Typical Facilities Services and Termination Matrix
 - Abolished SNARF Fall 2017 - Reapproval ballot failed Committee review, **new SNARF needs to be issued to reflect change in scope**
 - SEMI F47, Specification for Semiconductor Processing Equipment Voltage Sag Immunity
 - Failed committee review Spring 2018; **Voltage Sag Immunity TF to take over the revision of this document**
- Gases
 - Heater Jacket TF
 - SEMI F109, Guide for Heater Systems Requirements
 - Abolished Spring 2018; **new SNARF need to be issued for major revision (title cannot have Guide and Requirements)**

SNARF 3-year status

TC Chapter may grant a one-year extension

- Facilities
 - 5155, New Standard: Guide for Facilities Data Package for Semiconductor Equipment Installation
 - Expired – action to abolish
 - 6037, New Standard: Specification for Power Grid Harmonics Compatibility
 - Expired – action to abandon
 - 6313: Reapproval of SEMI F47-0706 (Reapproved 0812), Specification for Semiconductor Processing Equipment Voltage Sag Immunity
 - Expired – action to abolish
- None for Gases

SNARF(s) Approved by GCS in between TC Chapter Meetings

- 6582, New Standard: Test Method for Measuring Pitting Resistance of Stainless Steel Component

Thank you